Record Nr. UNINA9910437766803321 Autore Doll Joseph C Titolo Piezoresistor design and applications / / Joseph C. Doll, Beth L. Pruitt Pubbl/distr/stampa New York:,: Springer,, 2013 **ISBN** 1-4614-8517-7 Edizione [1st ed. 2013.] Descrizione fisica 1 online resource (xi, 245 pages): illustrations (some color) Microsystems and Nanosystems, , 2198-0063 Collana 620.1 Disciplina 621.3815 Soggetti Piezoelectric devices - Design and construction Electric resistors Microelectromechanical systems - Design and construction Lingua di pubblicazione Inglese **Formato** Materiale a stampa Livello bibliografico Monografia Note generali Description based upon print version of record. Nota di bibliografia Includes bibliographical references. Nota di contenuto Introduction -- Piezoresistance fundamentals -- Sensitivity, noise and resolution -- Fabrication and process modeling -- Temperature effects -- Design optimization -- Alternative materials and transduction methods. Sommario/riassunto This book is a comprehensive guide to piezoresistive MEMS sensor design. Piezoresistors transduce mechanical loads into electrical signals via a resistance change, and comprise a substantial portion of the commercial MEMS sensors market. Applications of piezoresistors include strain gauges, accelerometers, pressure sensors, force sensors, chemical sensors and resonators. This book also: . **Demonstrates** how the latest piezoresistor models and optimization techniques can be integrated for high performance piezoresistor design · in detail piezoresistor sensitivity and noise models, signal conditioning, fabrication processes, low-power design and numerical optimization Provides an up-to-date discussion of alternative techniques · piezoresistive materials and MEMS transduction techniques Explores in detail the tradeoffs in size, performance and complexity between piezoresistive sensing and popular alternatives (capacitive, piezoelectric and optical transduction) Piezoresistor Design and Applications addresses all aspects of piezoresistor design,

fabrication, modeling and optimization and is an ideal book for MEMS

designers, process engineers and researchers.